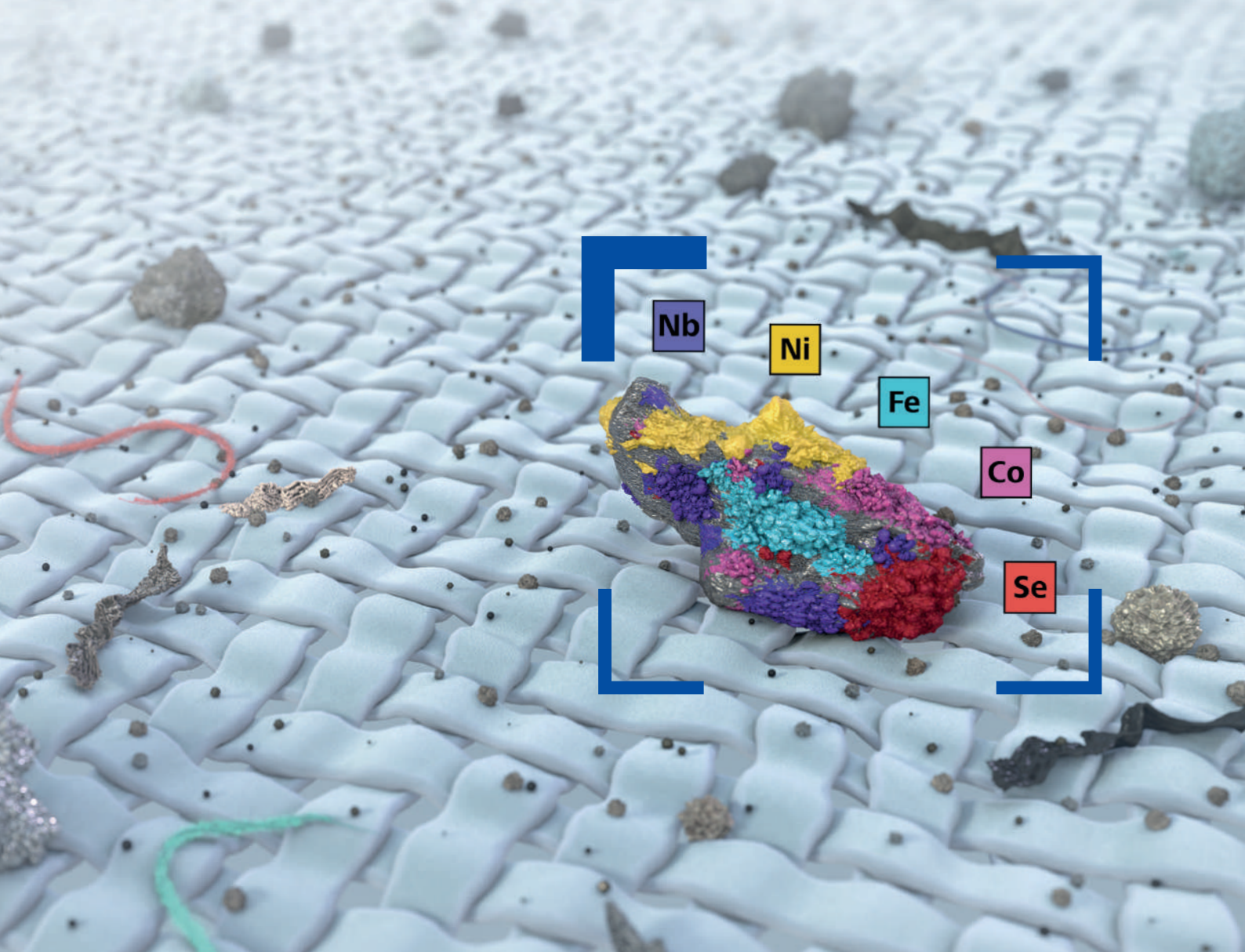


Identify the root cause.

Make the right
decision faster.



ZEISS Technical Cleanliness Solutions

Correlative workflow to identify particle contamination



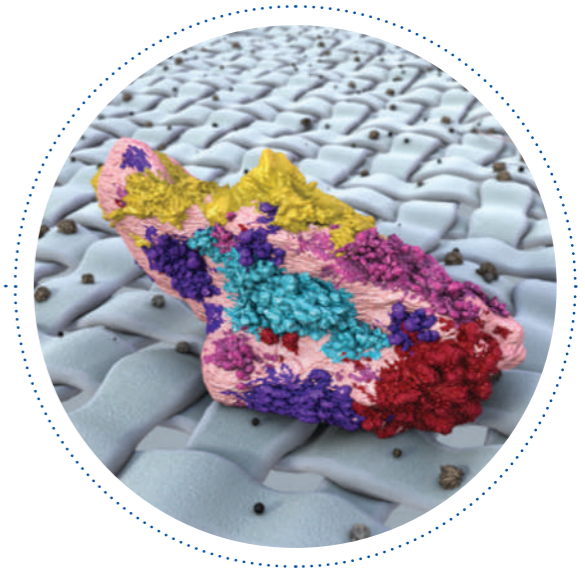
Particularly clean

Quality assured

Particle filters
from cleaning cabinet
or other particle
extraction methods



Critical particle
comprehensively
characterized



Particulate contamination is the enemy of any product's efficiency, functionality and longevity.

Suppliers, manufacturers and end users demand ever-increasing quality standards, so an advanced technical cleanliness program is fundamental to eradicating contamination of manufactured parts and components along the entire production process.

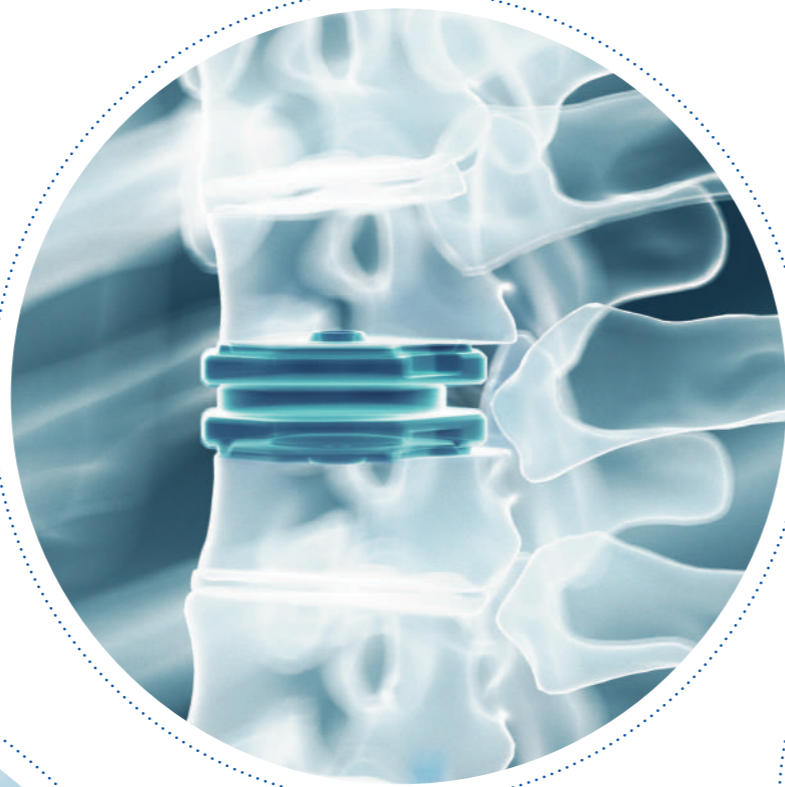
Additionally, investigations have shown that the major source of failure in hydraulic and oil-filled machines is based on particulate contamination. Oil analysis helps to minimize maintenance costs and improve machine uptime.

To achieve maximum quality, manufacturers need clear and comprehensive particle analysis data.

ZEISS Technical Cleanliness Solutions identify the root cause of contamination, allowing you to make the right decision faster.

Tailored precisely to the needs of manufacturing industries

Medical
Technology



Automotive
NEV



Additive
Manufacturing

Aerospace



ZEISS Technical Cleanliness Solutions were developed in collaboration with automotive companies. They had a specific need for powerful particle identification and classification systems, which had to be simple to use.

As a result, ZEISS solutions are easy to apply, can be deployed to multiple sites within any manufacturing or industrial environment and used by operators who are not microscopy experts.

ZEISS particle analysis solutions work with established industry standards:

Technical cleanliness

- VDA 19.1
- VDA 19.2
- ISO 16232

Oil cleanliness

- ISO 4406
- ISO 4007
- SAE AS 4059
- NAS 1638

Cleanliness of medical devices in the manufacturing process

- VDI 2083

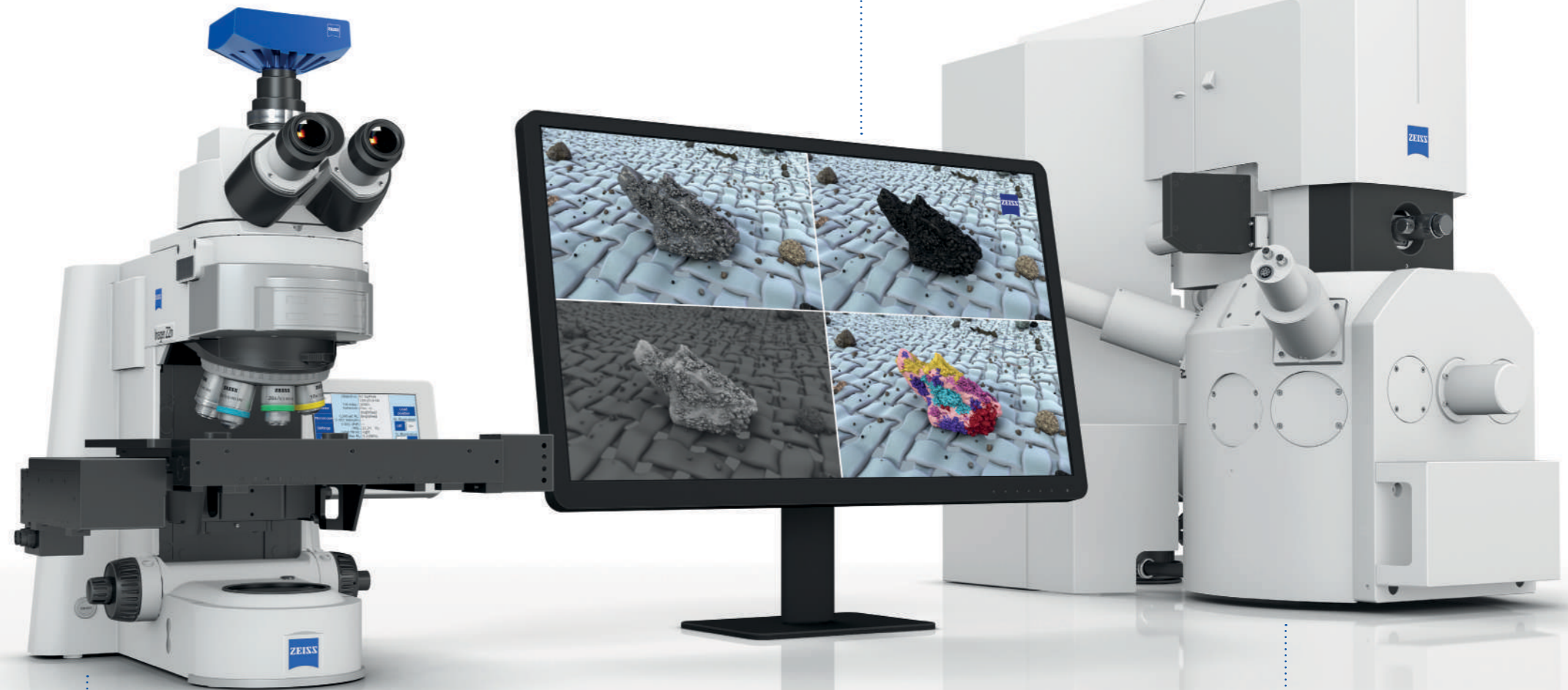
Go beyond standards

Make informed decisions about the root cause of contamination

ZEISS solutions for cleanliness testing not only allow you to quantify particulate contamination according to industry standards.

The ZEISS solution portfolio enables combined particle detection and classification in a highly efficient workflow that not only finds particles, but also helps to classify them by contamination or wear origin.

With ZEISS you can combine data from both light and electron microscopes in a single workflow to get more comprehensive information.



Correlative applications

Establish integrated work processes

Characterize process-critical particles and identify killer particles using correlative microscopy solutions (Shuttle & Find), which combines your data from both light and electron microscopes in a single workflow.

Seamless correlative workflow
& insights into particle origin



Light microscopy systems

Estimate potential risk for contamination

Itemize particles by quantity, size distribution and morphology, and distinguish metallic shiny from non-shiny particles and fibers down to 1 µm. Create cleanliness reports according to the most important industry standards.

Distinguish metallic shiny
vs. non-shiny particles



Electron microscopy and EDS systems

Pinpoint sources of contamination

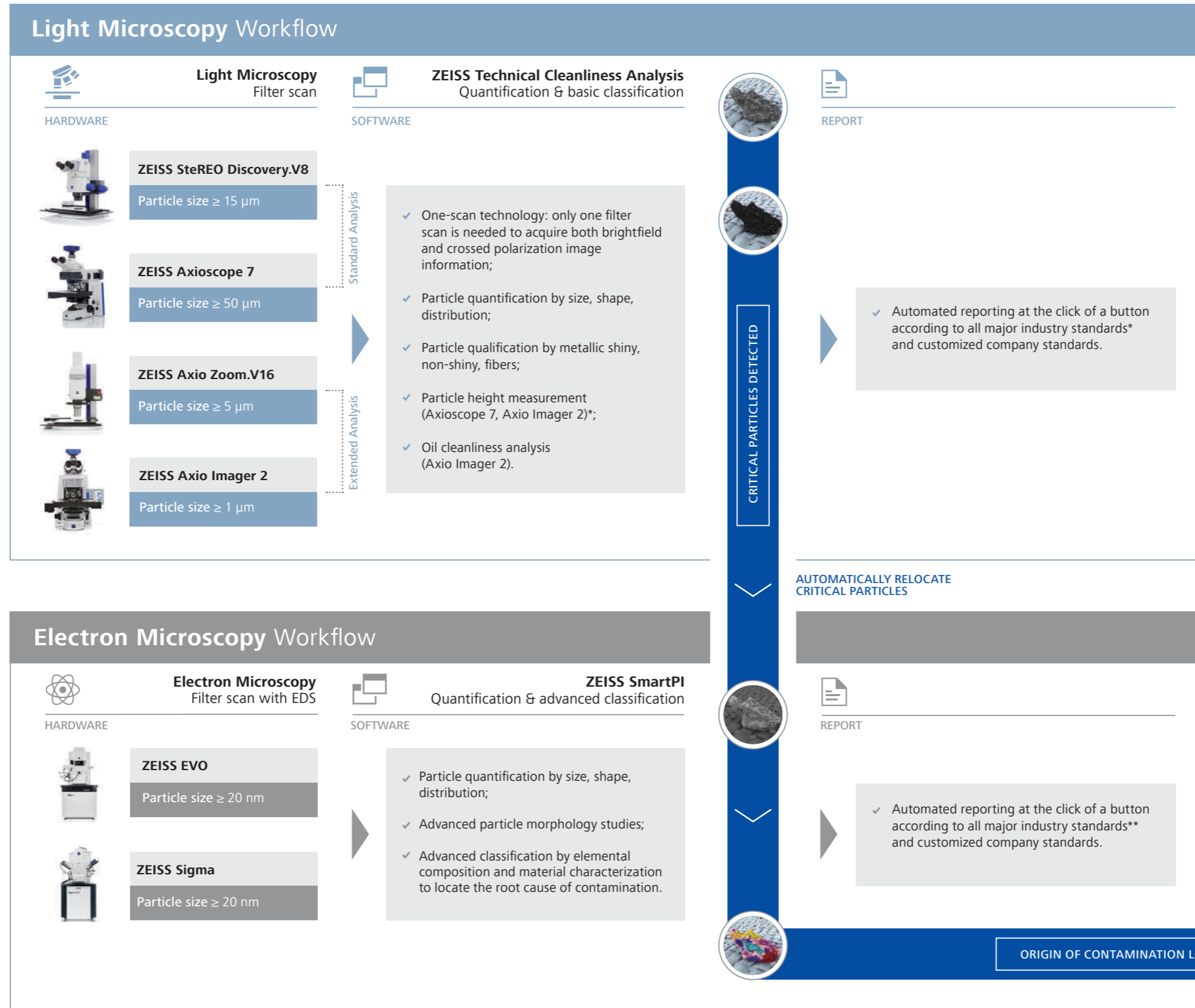
Measure morphological characteristics of particles and use fully automated elemental analyses to classify particles by their chemical composition.

Measures the elemental
composition of the metallic particles

Full color mapping
of all elements detected



Correlative Particle Analysis Workflow



ZEISS Shuttle & Find
Correlative Automated Particle Analysis

Correlated analysis across Light and Electron microscopy in a seamless integrated workflow

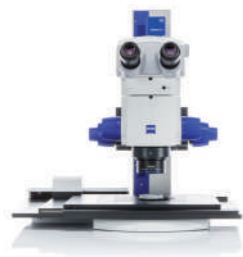
- ✓ Automatic integrated LM / EM reporting;
- ✓ Pinpoint sources of contamination;
- ✓ Make informed decisions faster;
- ✓ Continually improve production quality.

UP TO 10X FASTER RESULTS VERSUS CONSECUTIVE INDIVIDUAL ANALYSIS

** Supported industry standards: VDA 19.1, ISO 16232, ISO 4406, ISO 4007, SAE AS 4059, VDI 2083, NAS 1638

Light Microscopy Systems

ZEISS SteREO Discovery.V8



For particle size $\geq 15 \mu\text{m}$
Recommended for standard analyses according to VDA 19.1

Identify fibers and differentiate between metallic shiny and non-shiny particles with this cost-effective system for standard cleanliness testing applications.

ZEISS Axio Zoom.V16



For particle size $\geq 5 \mu\text{m}$
Recommended for extended analyses according to VDA 19.1

Perform accurate and repeatable analyses with this fully automated digital zoom microscope that supports rapid large field scanning and extended analyses requirements.

ZEISS Axio Imager 2



HARDWARE

For particle size $\geq 1 \mu\text{m}$
Recommended for advanced analyses, particle height measurement*, and oil analyses

Meet your high-resolution particle analyses requirements with this fully automated microscope for fast and precise measurement of particle length, width, and height*.

ZEISS Axioscope 7



HARDWARE



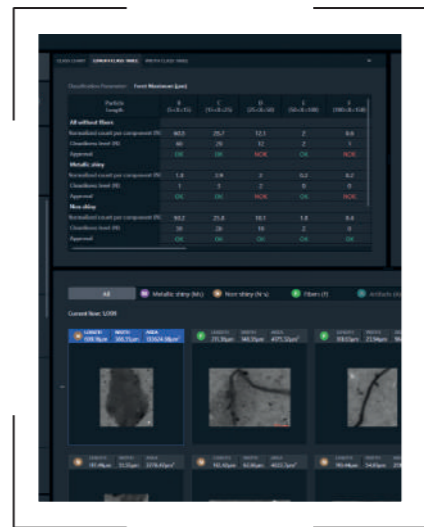
For particle size $\geq 50 \mu\text{m}$
Recommended for standard analyses according to VDA 19.1

Enable automation for your standard analysis. This microscope allows fully motorized axes of motion for automated imaging and height measurement (2020/21) in everyday operations.

ZEISS Technical Cleanliness Analysis



SOFTWARE



Particle analysis software for light microscopes

This easy-to-use software for standards-compliant cleanliness analyses enables the automated identification and classification of particles. Unlike conventional analysis methods, metallic shiny particles are detected with only one filter scan, which dramatically speeds up not only cleanliness reporting but also the identification of contamination sources. ZEISS Technical Cleanliness Analysis is part of ZEISS ZEN core, the software suite for connected microscopy, and can therefore be seamlessly integrated into extended analysis workflows. Regulatory requirements such as FDA21 CFR Part 11 can be fulfilled by the module GxP as optional part of the ZEN core TCA Software.

Electron Microscopy Systems

ZEISS EVO



C-SEM with EDS
Recommended for automated routine particle analyses

Utilize this SEM/EDS system for routine particle analyses applications. EVO is available with variable pressure (VP) to enable imaging and analysis of non-conductive samples, such as particle filter membranes.

ZEISS Sigma 360



FE-SEM with EDS
Recommended for high-resolution particle analyses

ZEISS Sigma 360 is the SEM of choice for particle analyses in the nanometer scale range. The system provides outstanding imaging results and is very well suited to elemental analysis, particularly on magnetic samples.

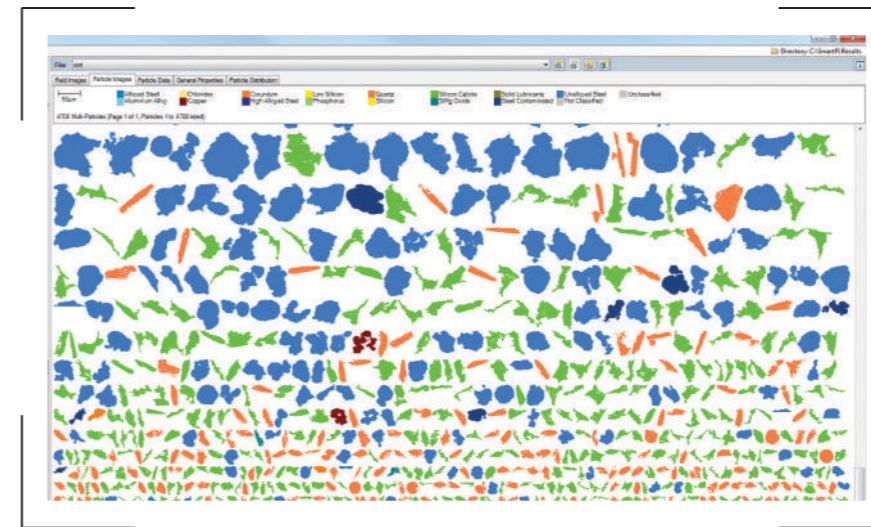


HARDWARE

ZEISS Smart PI



SOFTWARE



Particle analysis software for electron microscopes

SmartPI automates detection, analysis, and classification of particles, incorporating microscope control, image processing and elemental analysis within a single application. When used in correlative workflows, the software automatically retrieves critical particles previously identified under the light microscope, enabling rapid determination of chemical composition to identify the root cause of contamination quickly.

* Available as of 2021

Carl Zeiss IQS Deutschland GmbH

Carl-Zeiss-Straße 22
73447 Oberkochen, Deutschland
Tel.: +49 7364 20-6337
Fax: +49 7364 20-3870

info.metrology.de@zeiss.com
www.zeiss.de/imt

Carl Zeiss

Industrial Quality Solutions, LLC

6250 Sycamore Lane North
Maple Grove, MN 55369/USA

Phone: +1 800 327-9735

Fax: +1 763 533-0219

info.metrology.us@zeiss.com

www.zeiss.com/metrology